

# ACM Research, Inc.

August 2024 Investor Presentation



## **DISCLOSURES**

ACM

Forward-looking Statements. Certain statements contained in this presentation are not historical facts and may be forward-looking statements within the meaning of the Private Securities
Litigation Reform Act of 1995. Words such as "plans," "expects," "believes," "anticipates," "designed," and similar words are intended to identify forward-looking statements. Forward-looking
statements are based on ACM Research management's current expectations and beliefs and involve a number of risks and uncertainties that are difficult to predict and that could cause actual
results to differ materially from those stated or implied by the forward-looking statements. A description of certain of these risks, uncertainties and other matters can be found in filings ACM
Research makes with the U.S. Securities and Exchange Commission (the "SEC"), all of which are available at www.sec.gov. Because forward-looking statements involve risks and uncertainties,
actual results and events may differ materially from results and events currently expected by ACM Research. Readers are cautioned not to place undue reliance on these forward-looking
statements, which speak only as of the date hereof. ACM Research undertakes no obligation to publicly update these forward-looking statements to reflect events or circumstances that occur after
the date hereof or to reflect any change in its expectations with regard to these forward-looking statements or the occurrence of unanticipated events.

Market Data. Information presented below concerning ACM Research's total addressable market presents a forecast based on information provided by Gartner, Inc. in its report "Forecast: Semiconductor Wafer Fab Equipment, Worldwide, 4Q23 Update" (December 2023). You are cautioned not to rely on or give undue weight to this information. The Gartner report represents research opinions or viewpoints that are published, as part of a syndicated subscription service, by Gartner and are not representations of fact. The Gartner report speaks as of its original publication date (and not as of the date of this presentation), and the opinions expressed in the Gartner report are subject to change without notice. While ACM Research is not aware of any misstatements regarding the information provided in the Gartner report, it has not independently verified the accuracy or completeness of that information, which involves numerous assumptions and is subject to risks and uncertainties, as well as change based on various factors, that could cause results to differ materially from the forecast presented. The industry in which ACM Research operates is subject to a high degree of uncertainty and risk due to variety of factors, including those described in ACM Research's public filings with the SEC, as described above.

Note Regarding Presentation of Non-GAAP Financial Measures. Information presented below under "Q2 2024 Summary" and "Q2 2024 Financial Results" includes certain "non-GAAP financial measures" as defined in Regulation G under the Securities Exchange Act of 1934, including non-GAAP gross margin, non-GAAP operating income, non-GAAP basic and diluted EPS, and non-GAAP gross profit. These supplemental measures exclude the effect of stock-based compensation and unrealized gain or loss on short term investments, which ACM Research does not believe are indicative of its core operating results. A reconciliation of each non-GAAP financial measure to the most directly comparable GAAP financial measure is included below "Q2 2024 GAAP to Non-GAAP Reconciliation." ACM Research believes these non-GAAP financial measures are useful to investors in assessing its operating performance. ACM Research uses these financial measures internally to evaluate its operating performance and for planning and forecasting of future periods. Financial analysts may focus on and publish both historical results and future projections based on the non-GAAP financial measures. ACM Research also believes it is in the best interests of investors for ACM Research to provide this non-GAAP information.

While ACM Research believes these non-GAAP financial measures provide useful supplemental information to investors, there are limitations associated with the use of these non-GAAP financial measures. These non-GAAP financial measures may not be reported by competitors, and they may not be directly comparable to similarly titled measures of other companies due to differences in calculation methodologies. The non-GAAP financial measures are not an alternative to GAAP information and are not meant to be considered in isolation or as a substitute for comparable GAAP financial measures. They should be used only as a supplement to GAAP information and should be considered only in conjunction with ACM Research's consolidated financial statements prepared in accordance with GAAP.

SAPS, TEBO, ULTRA C, ULTRA Fn, Ultra ECP, Ultra ECP map, Ultra ECP ap and the ACM Research logo are ACM Research's trademarks. For convenience, these trademarks appear in this presentation without ™ symbols, but that practice does not mean that ACM Research will not assert, to the fullest extent under applicable law, its rights to the trademarks.

**Company References.** As used in this presentation, "ACM Shanghai" refers to ACM Research (Shanghai), Inc., "ACM South Korea" refers to Hanguk ACM CO., LTD, and "ACM Research" refers to ACM Research, Inc. and its subsidiaries, including ACM Shanghai and ACM South Korea.

## **ACM** Research at a Glance



- Multi-product supplier of semiconductor equipment to leading global semiconductor manufacturers
- Differentiated technology improves customer production processes with better yields and reduced chemical consumption
- More than 498 patents issued in the U.S., China, Japan, Singapore, South Korea and Taiwan as of 12/31/23
- State-of-the-art production facilities in Chuansha & Zhangjiang, Shanghai; construction nearly complete for new R&D and production center in Lingang, Shanghai
- Headquartered in Fremont, CA with more than 1,590 employees globally as of 12/31/23

## Cleaning

Flagship (SAPS, TEBO, Tahoe, Bevel Etch, SPM)















#### ECP, Furnace & Other

Ultra ECP ap Ultra ECP map

Ultra ECP ap-p

Ultra Fn Furnace









#### **NEW Products: Track and PECVD**

Track

PECVD





#### Advanced Packaging & Other

Scrubbers, coaters, developer tools, plating tools, tape frame cleaning, wet stripping, wet etching, panel level flux clean, and stress-free polishing systems, and other parts and services





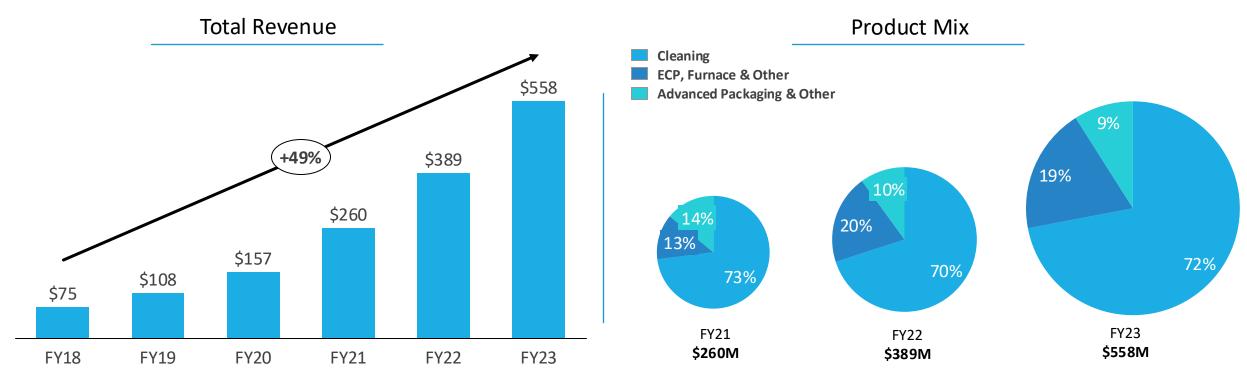






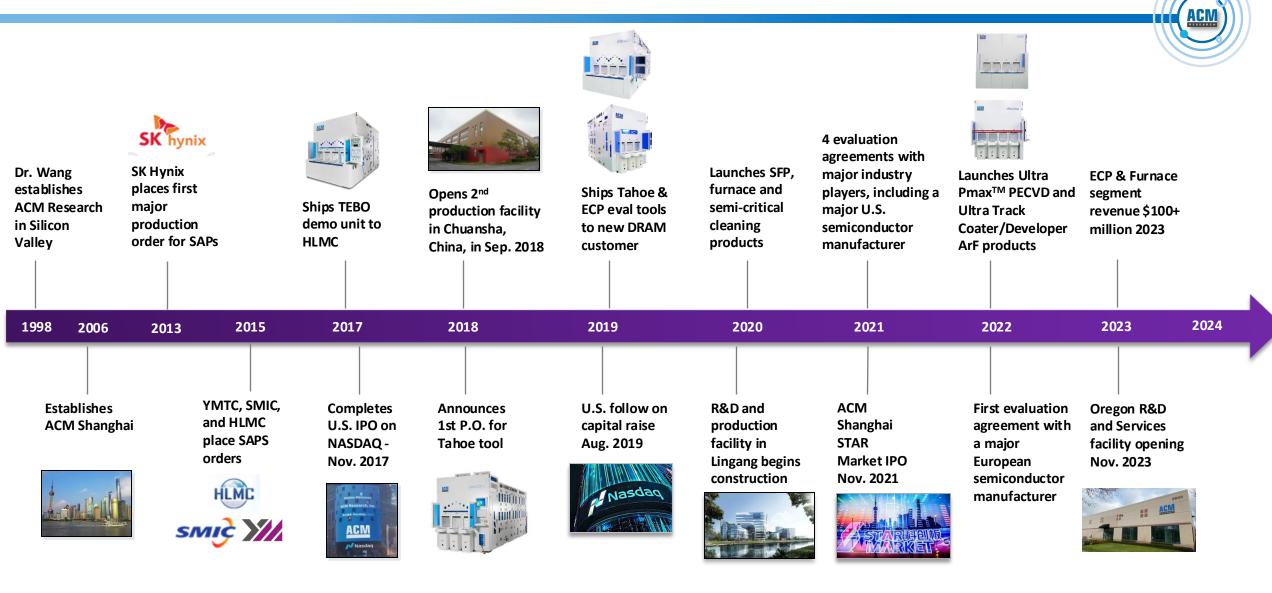
## **Financial Highlights**





- 1. <u>Cleaning</u>: Single wafer cleaning, Tahoe and semi-critical cleaning equipment
- 2. ECP, Furnace & Other: ECP (front-end and packaging), fumace and other technologies
- 3. Advanced Packaging & Other: Advanced Packaging (excluding ECP), services & spares

## **History of Innovation and Customer Design Wins**



## **Global Semiconductor Capital Equipment Supplier**









Shanghai R&D Center (Zhangjiang)



Shanghai Asia-Pacific Manufacturing Center >200,000 ft<sup>2</sup> (Chuansha)



Planned >1.4 million ft<sup>2</sup> (Lingang)

## **Tier 1 Customer Base**



#### **Front-End Customers**



- ACM Research 2023 Revenue %: 18%
- Mainland China's largest foundry
- Tier-one customers include Qualcomm,
  Broadcom and Texas Instruments (1)



- ACM Research 2023 Revenue %: 15%
- A semiconductor integrated circuit developer in China



- ACM Research 2023 Revenue %: 13%
- New China-based entrant to DRAM industry

#### **Back-End Customers**



- Largest bumping house in China and leading WLCSP production base
- Subsidiary of OSAT company JCET
- Owns one of the most advanced packaging technology R&D service platforms<sup>(3)</sup>
- Global customer base with exposure to the U.S., Western Europe and Asia



- Major new entrant into NAND flash and DRAM industry
- Innovative Xtacking 2.0 unleashes potential of 3D NAND (2)



Leading advanced foundry in China

## Tier 2 and 3 China-based IC Manufacturers

- Tier 2 includes Hangzhou Silan and 4 China-based customers
- Ordered a range of semi-critical tools including the scrubber, wet etch, and backside wafer etching tool, auto wet bench, SAPS-II cleaning tool and Cu interconnect ECP map tool.
- Tier 3 includes a handful of companies investing in new capacity in IoT, EV, AI



- Leading OSAT provider #4 globally<sup>(4)</sup> and top 3 in China<sup>(4)</sup>
- Fastest growing OSAT provider globally with ~30% year-over-year revenue growth in 2022<sup>(4)</sup>
- Six production facilities serving more than half of the top ten global semiconductor manufacturers<sup>(4)</sup>

(1) Source: SMIC website. (2) Source: YMTC Press Release. (3) Source: JCAP Company Profile. (4) Source: TFME website.

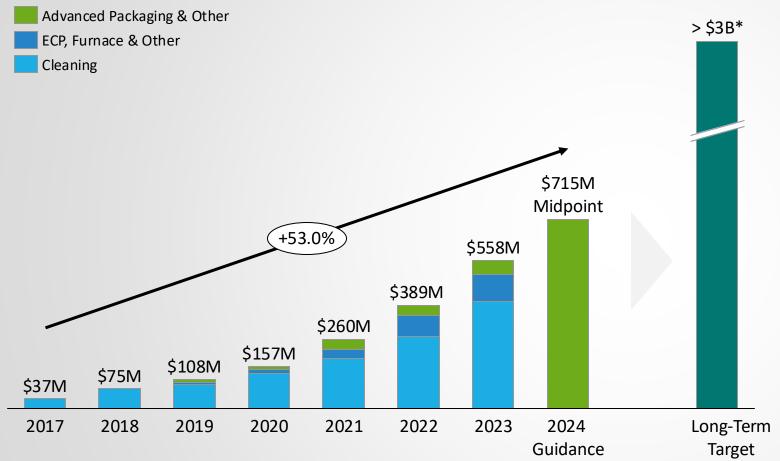
## Innovative Product Introductions Expanding Serviceable Available Market ("SAM")1

Estimated 2023 SAM of \$16 billion addressed by ACM Research's current product portfolio



## Long-Term Target for \$3B in Revenue





- 1. <u>Cleaning</u>: Single wafer cleaning, Tahoe and semi-critical cleaning equipment
- 2. ECP & Furnace & Other: ECP (front-end and packaging), furnace and other technologies
- 3. Advanced Packaging & Other: Advanced Packaging (excluding ECP), services & spares
- \* ACM Research internal target, for internal planning purposes only, not a projection or estimate of actual or future revenue

	Long-Term Target C	omposition					
			ACM Research				
Mainland China	ACM Research SAM <sup>1</sup>	China SAM <sup>2</sup>	Share <sup>3</sup>	Revenue			
Cleaning	\$5.2B	\$1.6B	55%	\$850M			
ECP	\$1.2	\$0.4	55%	\$200			
Furnace	\$2.2	\$0.7	15%	\$100			
PECVD	\$4.3	\$1.3	15%	\$200			
Track	\$2.5	\$0.8	10%	\$75			
Adv Pkg (ex ECP)	\$0.9	\$0.3	n/m	\$50			
Service & Spares	n/a	n/a	n/m	\$50			
	\$16B	\$5B	-	\$1.5B			
		Non-China					
RoW	ACM Research SAM	SAM <sup>1</sup>	Share <sup>3</sup>	Revenue			
Cleaning	\$5.2B	\$3.6B	20%	\$725M			
ECP	\$1.2	\$0.8	15%	\$125			
Furnace	\$2.2	\$1.5	10%	\$155			
PECVD	\$4.3	\$3.0	10%	\$300			
Track	\$2.5	\$1.8	10%	\$175			
Adv Pkg (Ex ECP)	\$0.9	\$0.9	n/m	\$50			
Service & Spares	n/a	n/a	n/m	\$50			
	\$16B	\$11B	<b>-</b>	\$1.5B			
<b>ACM Research Cl</b>	nina + RoW Revenue			>\$3.0B			

<sup>&</sup>lt;sup>1</sup>Source: Gartner - "Forecast: Semiconductor Wafer Fab Equipment, Worldwide, 4Q23 Update" (December 2023) and Company Estimates:

<sup>3</sup>Share refers to ACM Research market share target

<sup>■ 2023</sup> Gartner WFE market of \$93B

ACM Research SAM determined by management's estimated product coverage

<sup>&</sup>lt;sup>2</sup>China SAM assumes China is 30% of Global WFE

## **Growth Strategy**



## Growth at Existing Customers

- Continue winning share at existing customers
- Continued China fab expansion, particularly in mature nodes
- Accelerating ECP and furnace product cycles
- Solid evaluation pipeline for Track & PECVD

## **International Expansion**

- SAPS cleaning tool qualified for revenue by a large US manufacturer Q4'2023
- Delivered SAPS evaluation tool to major Europe-based global semiconductor manufacturer in Q3'2023
- Expanding sales & services teams in U.S., Europe, Korea and SE Asia
- R&D and Services facility in Hillsboro, Oregon
- Entered into an agreement to purchase 40,000 square feet R&D facility in Oregon with a fully-functional clean room



## **New Capacity**

- Lingang facility on track for initial production for 2H'2024 with target for longer term annual revenue production capacity of \$1.5 billion+
- Purchased new headquarters in Zhangjiang Shanghai, Silicon Valley of China
- Korea R&D and production facility to support international expansion



## **New Products**

- Broad product portfolio covering 90%+ of cleaning process steps including semi-critical, bevel etch, high-temp SPM, and super critical dry CO2.
- Plating for front and back end, furnace and semi-critical tools
- Added Track & PECVD product categories at end of 2022 that doubled ACM Research SAM to \$16 billion
- Launched two panel tools –plating and cleaning –to address the fan out panel level packaging market



## **Q2 2024 Summary**



#### **Q2 2024 Financial Results**

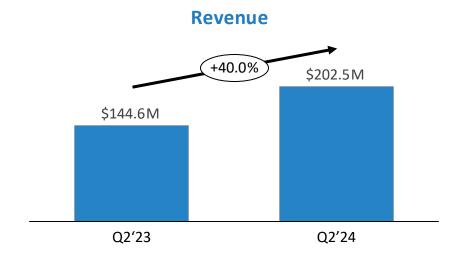
- \$202.5 million revenue (up 40.0% y/y); total shipments of \$203 million (up 32% y/y)
- 47.8% GAAP gross margin (versus 47.5% in Q2 2023)
- 48.2% non-GAAP gross margin (versus 47.6% in Q2 2023)
- \$37.6 million GAAP operating income (18.6% of revenue)
- \$51.9 million non-GAAP operating income (25.6% of revenue)
- \$0.35 diluted GAAP earnings per share (versus \$0.41 in Q2 2023)
- \$0.55 diluted non-GAAP earnings per share (versus \$0.48 in Q2 2023)

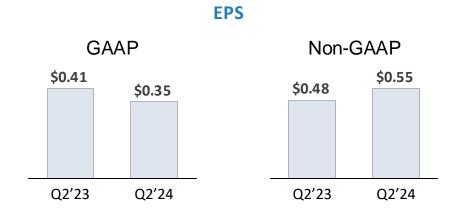
## **Key Operational Updates**

- Introduced Ultra ECP ap-p tool for fan-out panel-level packaging (FOPLP).
- Introduced Ultra C vac-p flux cleaning tool for FOPLP. Shipped to a new China-based packaging manufacturer in July.
- Received order from U.S. WLP house for a coater/developer tool, with delivery expected for 1H 2025.
- Initial production at Lingang production and R&D center expected to begin in 2H 2024.
- Entered into agreement to purchase R&D facility with clean room in Oregon.

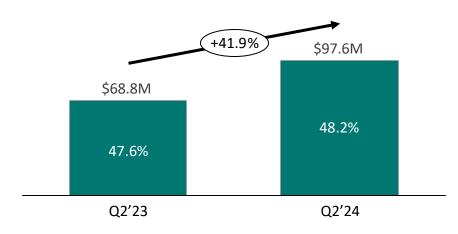
## **Q2 2024 Financial Results**



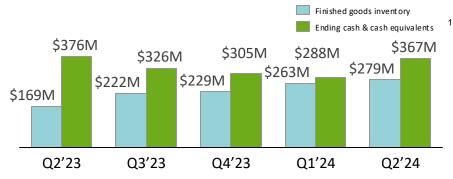




#### **Non-GAAP Gross Profit**



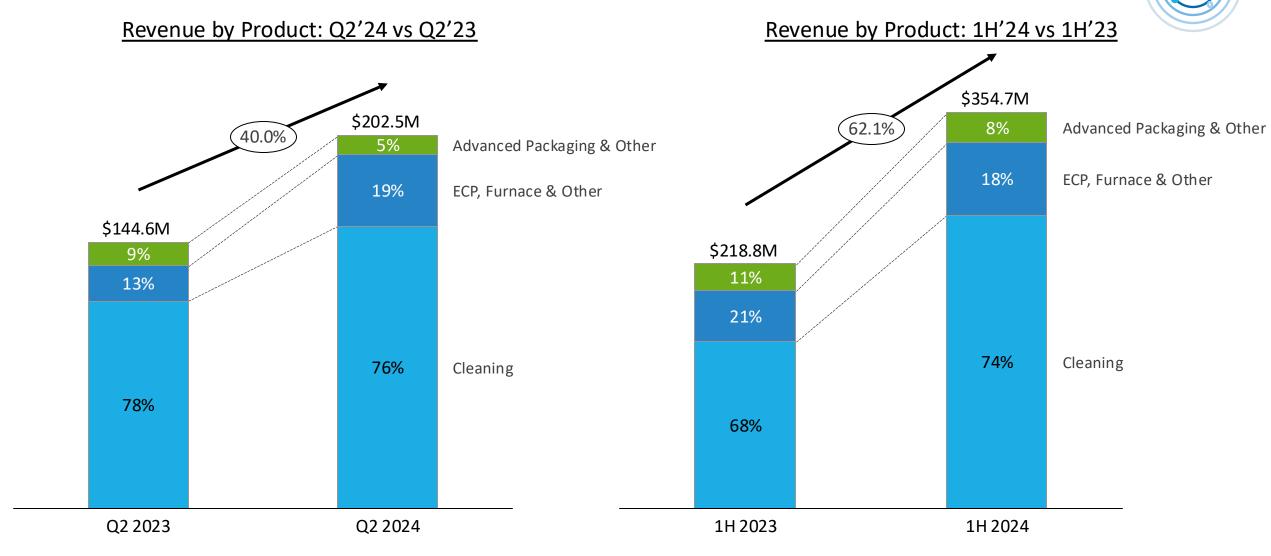
#### **Balance Sheet**



<sup>1</sup> Including interest bearing time deposits.

See slide 19 for reconciliation between GAAP and Non-GAAP Gross Profit and EPS

## Q2 and YTD 2024 Revenue Detail



<sup>1. &</sup>lt;u>Cleaning</u>: Single wafer cleaning, Tahoe and semi-critical cleaning equipment

<sup>2. &</sup>lt;u>ECP, Furnace & Other</u>: ECP (front-end and packaging), furnace and other technologies

<sup>3.</sup> Advanced Packaging & Other: Advanced Packaging (excluding ECP), services & spares

## **Wafer Cleaning**

# ACM

#### **Flagship Cleaning Tools**

#### **SAPS**

# that

Megasonic Cleaning for Flat and Patterned Wafer Surfaces

- O High efficiency with enhanced process flexibility
- Uniform and consistent resultsCustomizable specifications

5 TEBO



Bubble Oscillation Cleaning for Patterned Wafers at Advanced Process Nodes

- Highly effective, damage-free solution for small and fragile features
- Multi-parameter bubble cavitation control

#### Ultra – C Tahoe



Hybrid Wafer Cleaning With Significant Cost & Environmental Benefits

- Environmentally friendly uses 10% of the sulfuric acid used than conventional tools
- O High cleaning performance at low cost

#### **Bevel Etch**



Bevel Etching process for 3D NAND, DRAM and advanced logic processes

- Accurate and efficient wafer center alignment for precise bevel etch
- Variable wafer bevel etch/cut accuracy of 1-7mm and good uniformity

#### **Single Wafer High Temp SPM**



Single High Temp SPM Cleaning for metal removal and PR Strip at advance node

 Photoresist stripping after high-dose energy implant, wet stripping without using a dry ash process, and special metal film removal processes at advance node

#### **Semi Critical Cleaning Tools**

#### **Auto Bench**



Batch Wafer Cleaning for a full range of wet technologies across multiple nodes

- ULD advance drying technology addresses challenges in high-aspect-ratio structures
- MCR module delivers high cleaning performance
   and eliminates cross-contamination

#### Backside



Backside Clean Tool for wafer device side none contact process

- Good particle performance and etch uniformity control
- High throughput above 300 wp

#### Scrubber



Scrubber Cleaning for efficient frontand backside wet-cleaning applications

High throughput, small footprint and low costSmall particle removal

#### **Advance Processes**

#### **Supercritical CO2 Dry**



Supercritical CO2 Dry for advance DRAM processes

 Damage free drying process for highaspect-ratio structures including Isolation and Storage node

#### **High Temp IPA Dry (UTD)**



High Temp IPA Drying for advance Logic processes

 Damage free drying process for small structures and high-aspect-ratio structures
 Associate with customizable Cleaning method for good cleaning performance.

## **Electroplating**





Model	Ultra ECP map	Ultra ECP 3D	Ultra ECP ap	Ultra ECP ap (Cu-Ni-SnAg-Au)	Ultra ECP GIII	Ultra ECP ap-p
Application	Dual-damascene plating (90nm-28nm)	3D/2.5D high aspect ratio TSV	Pillar bump, Solder bump, RDL, Conformal TSV	High-density Fan Out Fine Pitch RDL	RF product 150mm wafer-level packaging	Pillar bump,RDL,U- pad 510*515mm2
	16 chambers	10/12 chambers	24/28 chambers	28 chambers	8/9 chambers	8/20 chambers
Module	Cu Post-cleaning Annealing	Cu Post-cleaning Pre-wetting	Cu+Ni+SnAg Pre-wetting Post-cleaning	Cu/Ni/SnAg/Au Pre-wetting Post-cleaning Cleaning after Au plating	Cu+Sn/Ag+Ni Au Pre-wetting Post-cleaning	Cu/Ni/SnAg/Au Pre-wetting Post-cleaning Buffer flip, aligner&CCD
Special Features	Impulse local plating	Impulse local plating	Second anode technology	Second anode technology Impulse Au plating	Second anode technology	Multi zone to control corner& edge paddle

## **Vertical Furnace**



Mask
Ox | Photo | Exposure | Develop | Etch | Ion | CVD | ALD | Metal | Wire |

Furnace Tube Classification	Film Type	Process	Temperature Range	Existing ACM Research Product	In Development
	Oxidation	Wet oxygen/dry	700~1200°C		
Normal Pressure	Annealing	oxygen/nitrogen annealing	700°1200°C	*	
Chemical Vapor Deposition Furnace	Back-end thermal	Copper process thermal treatment	100~450°C		
	treatment	Coating and curing	100 430 0		
Low Pressure	Alloy	Hydrogen/nitrogen thermal treatment	100~450°C	*	
		Poly-crystal silicon doping		*	
	Silicon deposition	Advanced poly-crystal deposition	500~620°C		☆
Chemical Vapor Deposition Furnace		No poly-crystal silicon doping		*	
	Silicon oxide	High-temperature silicon oxide	C50~000°C	*	
	Silicon nitride	Silicon nitride deposition	650~800°C	*	
Atomic Layer	Silicon oxide	Silicon oxide deposition	500~650°C		
Deposition Furnace	Silicon nitride	Silicon nitride deposition	500°650°C	*	



W\*L\*H= 1.10m\*3.70m\*4.05m

## **Advanced Packaging**



## Comprehensive solution for wafer-level advanced packaging wet process

# Cleaning



Scrubber

- Make use of ACM Research's technology advantages to expand application in Asia, especially advanced packaging manufacturers in China
- Dedicated to providing diversified and customer equipment meeting customer's designing requirements
- The products include scrubbers, coaters, developers, photoresist strippers, wet etchers, ECPs, and stress-free polishers

## Coating



Coater

Cleaning



Panel Level Flux Clean

Developing



Developer

**Wet Etching** 



Wet Etcher

**Plating** 



ECP





PR stripper

**Planarization** 



SFP

**Tape Frame Clean** 



Frame Wafer Cleaning

## **Track and PECVD**



Model	Model	Technical Features	Offline/Inline	Chamber Temperature	Bake Range	Development Phase
Ultra Lith™ Track Coater/Developer ——	ArF Model	<ul> <li>✓ Support 300mm wafers</li> <li>✓ Four 12-inch load ports</li> <li>✓ 8 coating chambers</li> <li>✓ 8 developing chambers</li> </ul>	Inline	23°C ±0.1°C	50~250°C	Industry Evaluation
	KrF Model	, -				In Development
	I-line Model					In Development

Model	Film Category	Film Type	RF Frequency	RF Control	Heater/CH	Development Phase
Ultra Pmax <sup>TM</sup> PECVD	SiH4 Base	SiO2; Si3N4; SiON	HF: 13.56MHz HF: 27.12MHz LF: 400KHz	Separate control	3	
	TEOS Base	TEOS Layer	HF: 13.56MHz HF: 27.12MHz LF: 400KHz	Separate control	3	Industry Evaluation
	Chemical Base	SiCN/APF Layer	HF: 13.56MHz HF: 27.12MHz LF: 400KHz	Separate control	3	

## Q2 2024 GAAP to Non-GAAP Reconciliation



Three	Months	Ended	June 30

		Three Working Engel					u ou	ounce,						
			20	24			2023							
		Actual	Actual		Other non- A			Actual (GAAP)			Other non- operating adjustments		Adjusted (Non-GAAP)	
		(GAAP)	SBC	operating adjustments		(Non-GAAP)				SBC				
						(In thousand	s)							
Revenue	\$	202,480	\$ -	\$ -	\$	202,480	\$	144,577	\$	-	\$ -	\$	144,577	
Cost of revenue		(105,696)	(792)	-		(104,904)		(75,938)		(125)	-		(75,813)	
Gross profit		96,784	(792)	-		97,576		68,639		(125)	-		68,764	
Gross margin		47.8%	0.4%	-		48.2%		47.5%		0.1%	-		47.6%	
Operating expenses:														
Sales and marketing		(17,135)	(3,024)	-		(14,111)		(11,439)		(431)	-		(11,008)	
Research and development		(25,968)	(4,206)	-		(21,762)		(20,064)		(709)	-		(19,355)	
General and administrative		(16,088)	(6,320)	-		(9,768)		(6,706)		(752)	-		(5,954)	
Total operating expenses 1		(59,191)	(13,550)	-		(45,641)		(38,209)		(1,892)	-		(36,317)	
Income (loss) from operations	\$	37,593	\$ (14,342)	\$ -	\$	51,935	\$	30,430	\$	(2,017)	\$ -	\$	32,447	
Unrealized gain (loss) on short-term investmen	nts	1,031	-	1,031		-		(2,455)		-	(2,455)		-	
Net income (loss) attributable to ACM Research, Inc.	\$	24,210	\$ (14,342)	\$ 1,031	\$	37,521	\$	26,825	\$	(2,017)	\$ (2,455)	\$	31,297	
Basic EPS	\$	0.39			\$	0.60	\$	0.45				\$	0.52	
Diluted EPS	\$	0.35			\$	0.55	\$	0.41				\$	0.48	